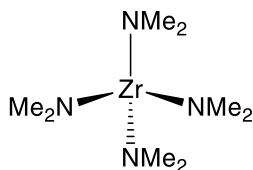


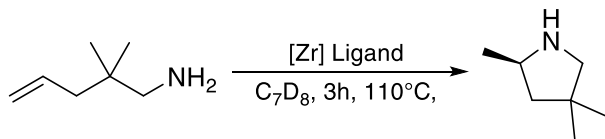
Catalog # 40-4100 Tetrakis(dimethylamino)zirconium(IV), 99% TDMAZ



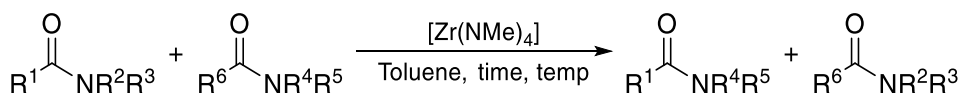
### Catalysis Applications

Technical Notes:

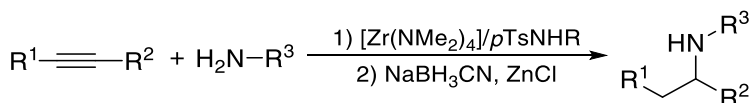
1. Catalyst for asymmetric intramolecular alkene hydroamination
2. Catalyst used for secondary amine-tertiary amide transamidations
3. Catalyst for the intermolecular hydroamination of alkynes with primary amines
4. Catalyst for the hydroaminoalkylation of alkynes to generate the allylic amines



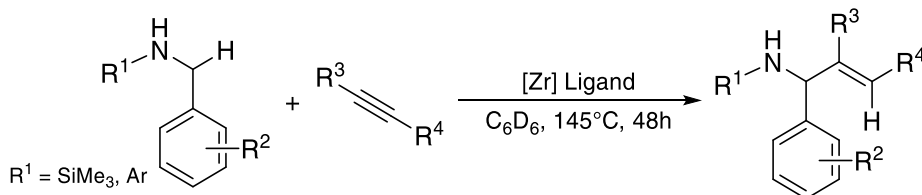
Tech Note (1)  
Ref. (1)



Tech Note (2)  
Ref. (2)



Tech Note (3)  
Ref. (3)



Tech Note (4)  
Ref. (4)

References:

1. [Angew. Chem. Int. Ed. 2007, 46, 354](#)
2. [J. Am. Chem. Soc. 2009, 131, 10003](#)
3. [Eur. J. Org. Chem. 2012, 764](#)
4. [J. Am. Chem. Soc. 2020, 142, 20566](#)

### CVD/ALD Applications

## Thermal Behavior:

- Melting Point: 60°C [1,2], 58°C [3]
- Boiling Point: 80°C/0.05 Torr [1]
- Vapor pressure: 0.1 Torr/49°C, 1 Torr/77°C [2]
- Decomposition: >250°C [10]

## Technical Notes:

1. ALD/CVD precursor for zirconium thin film deposition

| Target Deposit  | Deposition Technique | Delivery Temperature | Pressure       | Co-reactants   | Deposition Temperature | Ref.   |
|---|----------------------|----------------------|----------------|--|------------------------|--------|
| ZrO <sub>2</sub>  | ALD<br>PEALD         | 75°C                 | 1 Torr         | H <sub>2</sub> O   | 50-500°C<br>170-180°C  | 2<br>3 |
| ZrN <sub>x</sub>  | ALD                  | 75°C                 | 0.20-0.35 Torr | NH <sub>3</sub>  | 150-250°C              | 4      |
| Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub>              | ALD                  | -                    | -              | Hf(NMe <sub>2</sub> ) <sub>4</sub> , H <sub>2</sub> O<br>P <sup>L</sup> O <sub>2</sub> -H <sub>2</sub> | 175°C                  | 5<br>6 |
| (ZnTiZr) <sub>x</sub> O <sub>y</sub>                            | ALD                  | 85°C                 | 0.5 Torr       | Ti(NMe <sub>2</sub> ) <sub>4</sub> ,<br>ZnEt <sub>2</sub> , H <sub>2</sub> O                           | 200°C                  | 7      |
| Zr <sub>x</sub> Al <sub>1-x</sub> O <sub>y</sub>                | ALD                  | 60°C                 | 0.04 Torr      | AlMe <sub>3</sub> , H <sub>2</sub> O   | 250°C                  | 8      |
| SrZrO <sub>3</sub>  | ALD                  | 60°C                 | 1 Torr         | Sr(Pr <sub>3</sub> Cp) <sub>2</sub> , H <sub>2</sub> O   | 225°C                  | 9      |
| ZrO <sub>2</sub> /Y <sub>2</sub> O <sub>3</sub>                 | ALD                  | 100°C                | 0.2-0.3 Torr   | Y(MeCp) <sub>3</sub> , H <sub>2</sub> O  | 250°C                  | 10     |
| BaY <sub>x</sub> Zr <sub>y</sub> O <sub>z</sub>                 | ALD                  | 75°C                 | 0.1 Torr       | Ba(PrMe <sub>4</sub> Cp) <sub>2</sub><br>Y(MeCp) <sub>3</sub> , H <sub>2</sub> O                       | 250-270°C              | 11     |
| Li <sub>7</sub> La <sub>3</sub> Zr <sub>2</sub> O <sub>12</sub> | ALD                  | 80°C                 | -              | AlMe <sub>3</sub> , La-FMD,<br>LiOBu, O <sub>3</sub>   | 225°C                  | 12     |

## References:

1. [J. Chem. Soc., 1960, 3857](#)
2. [Chem. Mater. 2002, 14, 4350](#)
3. [ACS Appl. Mater. Interfaces 2018, 10, 32801](#)
4. [Chem. Mater. 2004, 16, 3497](#)
5. [Thin Solid Films 2019, 677, 142](#)
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10. [Chem. Mater. 2007, 19, 3850](#)
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12. [Chem. Mater. 2017, 29, 3785](#)